

Title (en)

MICROMETRIC MOVEMENT DEVICE AND METHOD FOR IMPLEMENTING SAME

Title (de)

MIKROMETERBEWEGUNGSVORRICHTUNG UND VERFAHREN ZU IHRER IMPLEMENTIERUNG

Title (fr)

DISPOSITIF DE DEPLACEMENT MICROMETRIQUE ET PROCEDE DE MISE EN OEUVRE.

Publication

**EP 2460199 A1 20120606 (FR)**

Application

**EP 10747923 A 20100727**

Priority

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- FR 2010000541 W 20100727

Abstract (en)

[origin: WO2011015722A1] The invention relates to a micrometric movement device, comprising a bending piezoelectric actuator (10) connected to a supporting and adjusting structure (20) via a decoupling means (30) including an inertial body (31), a portion of which is attached to the piezoelectric actuator, another portion being attached to a layer (32) secured to the supporting and adjusting structure, said layer being made of a material having a high capacity for absorbing vibrations, and having an energy dissipation factor  $\tan(\delta)$  of between 0.5 and 0.7 in a frequency range of 5 to 1000 Hz.

IPC 8 full level

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